

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Prior Application: N. HASEGAWA et al
Serial No. 10/096,599
Filed: March 14, 2002

Group Art Unit: 1756
Examiner: S. Rosasco
For: PHOTOMASK AND PATTERN FORMING METHOD
EMPLOYING THE SAME

INFORMATION DISCLOSURE STATEMENT (IDS)
UNDER § 1.97 AND § 1.98

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


February 13, 2004

Sir:

In accordance with the duty of disclosure, the Applicants inform the Examiner of the documents cited during prosecution of the parent application, USSN 10/096,599.

The Applicants request the Examiner to initial and return a copy of the attached PTO-1449 form as an indication that the references have been considered.

Respectfully submitted,


Daniel J. Stanger
Registration No. 32,846
Attorney for Applicant(s)

MATTINGLY, STANGER & MALUR, P.C.
1800 Diagonal Road, Suite 370
Alexandria, Virginia 22314
Telephone: (703) 684-1120
Facsimile: (703) 684-1157
Date: February 13, 2004

FORM PTO-1449 (REV. 7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. ASA-481-10		SERIAL NO.	
LIST OF DOCUMENTS CITED BY APPLICANT <i>(Use several sheets if necessary)</i>				APPLICANT N. HASEGAWA et al			
				FILING DATE 02/13/04		GROUP 1756	
U.S. PATENT DOCUMENTS							
* EXAMINER INITIAL	DOCUMENT	DATE	NAME	CLASS	SUBCLASS	FILING DATE <i>(If Appropriate)</i>	
	AA	5,429,897	07/04/95	Yoshioka et al			
	AB	5,589,305	12/31/96	Tomofuji et al			
	AC	5,472,813	12/1995	Nakagawa et al			
	AD	5,574,492	11/1996	Suzuki			
	AE	4,360,586	11/23/82	Flanders et al			
	AF	4,890,309	12/26/89	Smith et al			
	AG	5,328,807	07/12/94	Tanaka et al			
	AH	5,364,716	11/15/94	Nakagawa et al			
	AI	5,837,405	11/17/98	Tomofuji et al			
	AJ	5,660,956	08/26/97	Tomofuji et al			
	AK	5,595,844	01/21/97	Tomofuji et al			
FOREIGN PATENT DOCUMENTS							
	DOCUMENT	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO	
	AL	62-50811	10/27/87	Japan		<input type="checkbox"/>	<input type="checkbox"/>
	AM	4-136854	05/11/92	Japan		<input type="checkbox"/>	<input type="checkbox"/>
	AN	144453	06/19/91	Japan		<input type="checkbox"/>	<input type="checkbox"/>
	AO	269532	12/02/91	Japan		<input type="checkbox"/>	<input type="checkbox"/>
	AP	1750/95	02/28/95	Korea		<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, etc.)</i>							
	AR	Flanders et al, "Spatial period division - A new technique for exposing submicrometer-line width periodic and quasiperiodic patterns", JOURNAL OF VACUUM SCIENCE TECHNOLOGY, 16(6), Nov/Dec 1979, pp. 1949-1952					
	AS						
	AT						
EXAMINER				DATE CONSIDERED			
<small>* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

FORM PTO-1449 (REV. 7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. ASA-481-10		SERIAL NO.	
LIST OF DOCUMENTS CITED BY APPLICANT <i>(Use several sheets if necessary)</i>				APPLICANT			
				N. HASEGAWA et al			
				FILING DATE 02/13/04		GROUP 1756	
U.S. PATENT DOCUMENTS							
* EXAMINER INITIAL		DOCUMENT	DATE	NAME	CLASS	SUBCLASS	FILING DATE <i>(If Appropriate)</i>
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	AL	4-223464	08/13/92	Japan			<input type="checkbox"/> <input type="checkbox"/>
	AM	4-204653	07/27/92	Japan			<input type="checkbox"/> <input type="checkbox"/>
	AN						<input type="checkbox"/> <input type="checkbox"/>
	AO						<input type="checkbox"/> <input type="checkbox"/>
	AP						<input type="checkbox"/> <input type="checkbox"/>
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, etc.)</i>							
	AR						
	AS						
	AT						
EXAMINER				DATE CONSIDERED			
<small>* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							